

10/501672

DT04 Rec'd PCT/PTO 16 JUL 2004

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of

Hiroshi TAKENO

: **Mail Stop: PCT**

Serial No. NEW

: Attorney Docket No. 2004_1129A

Filed July 16, 2004

SILICON EPITAXIAL WAFER AND PROCESS FOR
MANUFACTURING THE SAME
[Corresponding to PCT/JP03/00345
Filed January 17, 2003]

PRELIMINARY AMENDMENT

Commissioner for Patents

P.O. Box 1450

Alexandria, VA 22313-1450

Sir:

Prior to calculating the filing fee, please amend the above-identified application as follows:

Amendments to the Title

Please replace the title with the following new title:

**SILICON EPITAXIAL WAFER AND PROCESS FOR MANUFACTURING THE
SAME**

Immediately after the title, please insert the following sentence:

**This application is a U.S. national stage of International Application No.
PCT/JP03/00345 filed January 17, 2003.**